

In the Claims:

Please amend the Claims as follows:

1. (Currently Amended) A method of forming a via contact structure, the method comprising the steps of:

forming a lower interconnection line ~~on~~over a semiconductor substrate;

sequentially forming an inter-metal dielectric layer and a hard mask layer on an entire surface of the semiconductor substrate having the lower interconnection line;

patterning the hard mask layer and the inter-metal dielectric layer to form a via hole exposing the lower interconnection line;

forming a sacrificial layer filling the via hole on the hard mask layer;

forming an anti-reflective layer on the sacrificial layer;

patterning the sacrificial layer, the anti-reflective layer, and the hard mask layer to form a first sacrificial layer pattern having an opening that crosses over the via hole and a second sacrificial layer pattern that remains in the via hole, and to simultaneously form a hard mask pattern underneath the first sacrificial layer pattern;

partially etching the inter-metal dielectric layer using the hard mask pattern as an etching mask to form a trench crossing over the via hole; and

removing the second sacrificial layer pattern to expose the lower interconnection line.

2-4. (Canceled)

5. (Original) The method according to claim 1, wherein the inter-metal dielectric layer is formed of a single layer of insulating material, the trench being formed to a depth less than the total thickness of the inter-metal dielectric layer.

6. (Original) The method according to claim 1, wherein the inter-metal dielectric layer is formed by sequentially stacking a lower inter-metal dielectric layer, a trench etch stop layer and an upper inter-metal dielectric layer, the trench being formed by etching the upper inter-metal dielectric layer until the trench etch stop layer is exposed.

7. (Original) The method according to claim 6, wherein the trench etch stop layer is formed of an insulating nitride layer or an insulating carbide layer that has an etching selectivity with respect to the upper inter-metal dielectric layer.

8. (Original) The method according to claim 7, wherein the insulating nitride layer is a silicon nitride layer, a silicon carbonitride layer (SiCN) or a boron nitride layer (BN), and the insulating carbide layer is a silicon carbide layer (SiC).

9. (Original) The method according to claim 1, wherein the hard mask layer is formed of an insulating nitride layer, an insulating carbide layer, a metal nitride layer, a metal oxide layer or a silicon layer that has an etching selectivity with respect to the

inter-metal dielectric layer and the sacrificial layer.

10. (Original) The method according to claim 9, wherein the insulating nitride layer is a silicon nitride layer (SiN), a silicon carbonitride layer (SiCN) or a boron nitride layer (BN), the insulating carbide layer is a silicon carbide layer (SiC), the metal nitride layer is a tantalum nitride layer or a titanium nitride layer, the metal oxide layer is an aluminum oxide layer (Al₂O₃), a tantalum oxide layer or a titanium oxide layer, and the silicon layer is a polycrystalline silicon layer or an amorphous silicon layer.

11. (Original) The method according to claim 1, wherein the sacrificial layer is formed of an inorganic material layer.

12. (Original) The method according to claim 11, wherein the inorganic material layer is a hydro-silses-quioxane (HSQ) layer formed by using a spin coating technique.

13. (Canceled)

14. (Currently Amended) The method according to claim 1, wherein the step of patterning the sacrificial layer, the anti-reflective layer, and the hard mask layer ~~comprising~~ comprises the sub-steps of:

forming a photoresist pattern on the sacrificial layer and the anti-reflective layer, the photoresist pattern having an opening that crosses over the via hole;

etching the anti-reflective layer and the sacrificial layer using the photoresist pattern as an etching mask to form the first sacrificial layer pattern having an opening that crosses over the via hole and the second sacrificial layer pattern that remains in the via hole;

removing the photoresist pattern; and

etching the hard mask layer using the first sacrificial layer pattern as the etching mask to form the hard mask pattern underneath the first sacrificial layer pattern.

15. (Currently Amended) The method according to claim 1, wherein the step of patterning the anti-reflective layer, the sacrificial layer and the hard mask layer ~~comprising~~ comprises the sub-steps of:

forming a photoresist pattern on the anti-reflective layer and the sacrificial layer, the photoresist pattern having an opening that crosses over the via hole;

successively etching the sacrificial layer-, the anti-reflective layer and the hard mask layer using the photoresist pattern as an etching mask to form the first sacrificial layer pattern having an opening that crosses over the via hole and the second sacrificial layer pattern that remains in the via hole, and to simultaneously form the hard mask pattern underneath the first sacrificial layer pattern; and

removing the photoresist pattern.

16. (Original) The method according to claim 1 further comprising the steps of:
forming an upper metal layer by depositing a metal layer on the semiconductor

substrate including the via hole and the trench after removal of the second sacrificial layer pattern, wherein the via hole and the trench are filled with the metal layer; and planarizing the upper metal layer to form an upper metal interconnection line.

17. (Original) The method according to claim 16, wherein the upper metal layer is formed by sequentially stacking a diffusion barrier layer and the metal layer.

18. (Currently Amended) A method of forming a via contact structure, the method comprising the steps of:

forming a lower interconnection line ~~on~~over a semiconductor substrate;

sequentially forming a via etch stop layer, a lower inter-metal dielectric layer, a trench etch stop layer, an upper inter-metal dielectric layer and a hard mask layer on an entire surface of the semiconductor substrate having the lower interconnection line;

patterning the hard mask layer, the upper inter-metal dielectric layer, the trench etch stop layer and the lower inter-metal dielectric layer to form a preliminary via hole that exposes the via etch stop layer on the lower interconnection line;

forming a sacrificial layer filling the preliminary via hole on the hard mask layer;

forming an anti-reflective layer on the sacrificial layer;

patterning the anti-reflective layer, the sacrificial layer and the hard mask layer to form a first sacrificial layer pattern having an opening that crosses over the preliminary via hole and a second sacrificial layer pattern that remains in the ~~preliminary~~preliminary via hole, and to simultaneously form a hard mask pattern underneath the first sacrificial

layer pattern;

etching the upper inter-metal dielectric layer using the hard mask pattern and the trench etch stop layer as an etching mask and an etch stop layer ~~respectively~~ respectively, thereby forming a trench in the upper inter-metal dielectric layer;

selectively removing the second sacrificial layer pattern to expose the via etch stop layer; and

etching the exposed via etch stop layer to form a final via hole that exposes the lower interconnection line.

19. (Original) The method according to claim 18, wherein the via etch stop layer is formed of an insulating nitride layer or an insulating carbide layer that has an etching selectivity with respect to the lower inter-metal dielectric layer.

20. (Original) The method according to claim 19, wherein the insulating nitride layer is a silicon nitride layer (SiN), a silicon carbonitride layer (SiCN) or a boron nitride layer (BN), and the insulating carbide layer is a silicon carbide layer (SiC).

21. (Original) The method according to claim 20, wherein the trench etch stop layer is formed of an insulating nitride layer or an insulating carbide layer that has an etching selectivity with respect to the upper inter-metal dielectric layer.

22. (Original) The method according to claim 21, wherein the insulating nitride

layer is a silicon nitride layer, a silicon carbonitride layer (SiCN) or a boron nitride layer (BN), and the insulating carbide layer is a silicon carbide layer (SiC).

23. (Original) The method according to claim 18, wherein the hard mask layer is formed of an insulating nitride layer, an insulating carbide layer, a metal nitride layer, a metal oxide layer or a silicon layer that has an etching selectivity with respect to the upper inter-metal dielectric layer and the sacrificial layer.

24. (Original) The method according to claim 23, wherein the insulating nitride layer is a silicon nitride layer (SiN), a silicon carbonitride layer (SiCN), or a boron nitride layer (BN), the insulating carbide layer is a silicon carbide layer (SiC), the metal nitride layer is a tantalum nitride layer or a titanium nitride layer, the metal oxide layer is an aluminum oxide (Al₂O₃) layer, a tantalum oxide layer or a titanium oxide layer, and the silicon layer is a polycrystalline silicon layer or an amorphous silicon layer.

25. (Canceled)

26. (Currently Amended) The method according to claim 18, wherein the step of patterning the anti-reflective layer, the sacrificial layer and the hard mask layer comprises ~~comprising~~ the sub-steps of:

forming a photoresist pattern on the anti-reflective layer and the sacrificial layer, the ~~photoresist~~ photoresist pattern having an opening that crosses over the preliminary

via hole;

etching the anti-reflective layer and the sacrificial layer using the photoresist pattern as an etching mask to form the first sacrificial layer pattern having an opening that crosses over the preliminary via hole and the second sacrificial layer pattern that remains in the preliminary via hole;

removing the photoresist pattern; and

etching the hard mask layer using the first sacrificial layer pattern as the etching mask to form the hard mask pattern underneath the first sacrificial layer pattern.

27. (Currently Amended) The method according to claim 18, wherein the step of patterning the anti-reflective layer, the sacrificial layer and the hard mask layer ~~comprising~~ comprises the sub-steps of:

forming a photoresist pattern on the anti-reflective layer and the sacrificial layer, the photoresist pattern having an opening that crosses over the preliminary via hole;

successively etching the sacrificial layer and the hard mask layer using the photoresist pattern as an etching mask to form the first sacrificial layer pattern having an opening that crosses over the preliminary via hole and the second sacrificial layer pattern that remains in the preliminary via hole, and to simultaneously form the hard mask pattern underneath the first sacrificial layer pattern; and

removing the photoresist pattern.

28. (Original) The method according to claim 18 further comprising the steps of:

forming an upper metal layer by depositing a metal layer on the semiconductor substrate including the final via hole and the trench after formation of the final via hole, wherein the final via hole and the trench are filled with the metal layer; and

planarizing the upper metal layer to form an upper metal interconnection line.

29. (Original) The method according to claim 28, wherein the upper metal layer is formed by sequentially stacking a diffusion barrier layer and the metal layer.

30. (Original) The method according to claim 16, wherein the hard mask pattern is formed of a conductive layer or a semiconductor layer, the hard mask pattern is removed during or after the planarization process.

31. (Original) The method according to claim 28, wherein the hard mask pattern is formed of a conductive layer or a semiconductor layer, the hard mask pattern is removed during or after the planarization process.

32. (Currently Amended) A method of forming a via contact structure, the method comprising the steps of:

forming a lower interconnection line ~~on~~over a semiconductor substrate;

forming a via etch stop layer on the semiconductor substrate having the lower interconnection line;

sequentially forming an inter-metal dielectric layer and a hard mask layer on an

entire surface of the semiconductor substrate having the lower interconnection line;

 patterning the hard mask layer and the inter-metal dielectric layer to form a preliminary via hole exposing a surface of the via etch stop layer;

 forming a sacrificial layer filling the via hole on the hard mask layer;

 forming an antireflective layer on the sacrificial layer;

 patterning the antireflective layer, the sacrificial layer and the hard mask layer to form a first sacrificial layer pattern having an opening that crosses over the via hole and a second sacrificial layer pattern that remains in the via hole, and to simultaneously form a hard mask pattern underneath the first sacrificial layer pattern;

 partially etching the inter-metal dielectric layer using the hard mask pattern as an etching mask to form a trench crossing over the via hole;

 removing the second sacrificial layer pattern to expose the surface of the via etch stop layer; and

 removing the via etch stop layer to form a final via hole that exposes the lower interconnection line.